

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: Not yet assigned
Applicants: Christian DUSSARRAT, et al.
Filed Internationally: April 8, 2004
US National: Herewith
Title: METHODS FOR PRODUCING SILICON NITRIDE FILMS BY
VAPOR-PHASE GROWTH
TC/A.U: Unknown
Examiner: Unknown
Docket No.: Serie 6070
Customer No.: 000040582

INFORMATION DISCLOSURE STATEMENT

Commissioner of Patents
P.O. Box 1450
Washington, D.C. 20231

Dear Sir:

In accordance with the duty of disclosure as set forth in 37 C.F.R. § 1.56, Applicants hereby submit the following information in conformance with 37 C.F.R. §§ 1.97 and 1.98. Pursuant to 37 C.F.R. § 1.98, a copy of each of the non-US patent documents cited on the enclosed PTO Form 1449 is enclosed.

No fee is due at this time in accordance with 37 C.F.R. § 1.97. However, the Commissioner is hereby authorized to charge any appropriate fees under 37 C.F.R. §§ 1.16, 1.17 and 1.21 that may be required by this paper, and to credit any overpayment, to Deposit Account No. 01-1375. This paper is submitted in duplicate.

Respectfully submitted,

Date: **October 17, 2005**



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